



Attorney Docket No.: AMD-AF01214

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE
Patent Application

Inventor(s): YANG, et al,

Group Art Unit:

Filed: 01/14/2004

Examiner:

Application No.: 10/758,148

Conf No.: 4639

Title: EFFICIENT USE OF WAFER AREA WITH DEVICE UNDER THE PAD APPROACH

Form 1449

U.S. Patent Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class	Filing Date
LP	A	5,751,065	05/12/98	CHITTIPEDDI, et al.	257	758	10/30/95
	B						
	C						
	D						
	E						
	F						
	G						
	H						
	I						
	J						
	K						

Foreign Patent or Published Foreign Patent Application

Examiner Initial	No.	Document No.	Publication Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No
LP	L	EP0637840	02/08/95	EPO	H01L	23/485	X	
	M	WO00/35013	06/12/00	PCT	H01L	23/485	X	
	N	JP 332045	11/30/00	JP	H01L	21/60		X
	O	JP 321104	12/12/97	JP	H01L	21/66		X
	P	JP 335627	12/18/98	JP	H01L	27/148		X
	Q							

Other Documents

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
	R	
	S	
	T	
Examiner:	LUNH PHAM	
	Date Considered	6/7/05

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.